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U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

**NOTICE OF APPEAL AND
REQUEST FOR
EXTENSION OF TIME
PURSUANT TO 37 C.F.R. § 1.136(a)**

Docket Number:
10191/1466

Conf. No.:
4295

Application Number
09/581,663

Filing Date
August 3, 2000

Examiner
Shamim AHMED

Art Unit
1765

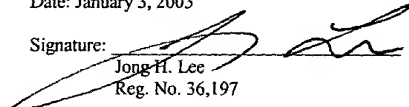
Invention Title
**METHOD FOR PROCESSING SILICON BY
ETCHING PROCESSES**

Inventor(s)
Volker BECKER et al.

Commissioner for Patents
Washington, D.C. 20231

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to Commissioner for Patents, Washington, D.C. 20231 on

Date: January 3, 2003

Signature: 
Jong H. Lee
Reg. No. 36,197

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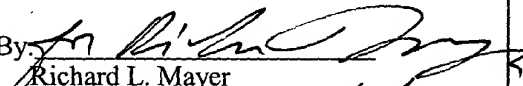
Applicants hereby appeal to the Board of Patent Appeals and Interference from the decision of the Examiner made in the Final Office Action dated July 5, 2002 finally rejecting claims 33, 34, 36-38 and 62.

Applicants also respectfully request a three-month extension of time in which to respond to the Final Office Action for which a response period expiring on October 5, 2002 was set. The extended period now expires on January 5, 2003.

The Commissioner is hereby authorized to charge payment of the 37 C.F.R. § 1.191 Notice of Appeal fee of **\$320.00** and the 37 CFR §1.136(a) extension fee of **\$930.00** to the deposit account of **Kenyon & Kenyon**, deposit account number **11-0600**. The Commissioner is also authorized to charge any additional fees or credit any overpayment in connection with this paper to Deposit Account No. 11-0600.

Respectfully submitted,

Dated: January 3, 2003

By: 
Richard L. Mayer
Reg. No. 22,490
KENYON & KENYON

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